

<b>Notice of References Cited</b>	Application/Control No. 09/815,879	Applicant(s)/Patent Under Reexamination DOSHITA ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	W	MicroSim Pspice & Basics: User's Guide. Chapter 13, "Analyzing Waveforms in Probe". June, 1997. pp.13-1 to 13-23.
	X	Hageman, S. "Use Ferrite Bead Models to analyze EMI Suppression." MicroSim Application Notes. June, 1997. pp.240-251.

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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